

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1-8. (Cancelled).

9. (Currently Amended) A micro electromechanical switching arrangement, comprising:

a switching element ~~comprising~~ including a first support, an actuator control electrode, and a switching beam having a first end and a second end, the first end of the switching beam being supported by the first support, ~~characterized in that the micro electromechanical switching arrangement further comprises;~~

[-] a switching beam position measurement device, ~~which generates for~~ generating a beam position signal related to a position of the switching beam in relation to a position of the actuator control electrode; and

[-] an actuator control signal unit, ~~which generates for~~ generating an actuator control signal in dependence on the beam position signal and a desired switching beam position signal, the actuator control signal being coupled to the actuator control electrode.

10. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, ~~characterized in that:~~ wherein [-] the switching element further comprises a second support, the second end of the switching beam being supported by the second support.

11. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, ~~characterized in that:~~ wherein [-] the switching beam position measurement device ~~utilizes~~ is configured to use capacitive measurement methods for generating the beam position signal.

12. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, ~~characterized in that:~~ wherein [-] the switching beam position measurement device comprises a variable capacitance element and a Wheatstone bridge in which the variable capacitive device is one element.